

## **AMENDMENTS TO THE CLAIMS**

### **Claims 1-19 (Canceled)**

**Claim 20 (New)**      A system for supplying a semiconductor manufacturing system control program, comprising:

an administrative server operable to transmit a replacement semiconductor manufacturing system control program;

a communications circuit operable to connect the administrative server to a controller of a semiconductor manufacturing system;

a determination unit provided in said controller that is operable to determine a time when a previously installed control program can be changed wherein a time when the semiconductor manufacturing system is performing a process event for growing a film on a substrate that is undergoing processing is not a time when the control program can be changed; and

a storing unit provided in said controller that is responsive to a result of the determination unit for storing the replacement semiconductor manufacturing system control program received from said administrative server through said communications circuit in a memory so as to be executable by a processor.

**Claim 21 (New)**      The system of claim 20, and further comprising a retaining unit provided in said controller for retaining existing data used to execute the previously installed control program, said controller being operable to execute the replacement semiconductor manufacturing system control program stored in the memory using the existing data.

**Claim 22 (New)**      A method for supplying a semiconductor manufacturing system control program through a communications circuit to a controller for controlling operation of a semiconductor manufacturing system, said method comprising:

transmitting a semiconductor manufacturing system control program through a communications circuit to a controller of a semiconductor manufacturing system;

storing the semiconductor manufacturing system control program sent by said transmitting so as to be executable by the controller and at a time when the semiconductor manufacturing system is in an operating state which permits a previously installed control program to be changed, wherein a time when the semiconductor manufacturing system is performing a process event for growing a film on a substrate that is undergoing processing is not a time when the control program can be changed.

**Claim 23 (New)** The method of claim 22, further comprising executing the transmitted and stored semiconductor manufacturing system control program using data used to execute a previously installed control program.

**Claim 24 (New)** An administrative server for supplying a semiconductor manufacturing system control program through a communications circuit to a controller for controlling operation of a semiconductor manufacturing system control program through a communications circuit to a controller for controlling operation of a semiconductor manufacturing system by execution of a control program, said administrative server comprising a transmitting unit operable to transmit a control program through a communications circuit to a controller for, when the semiconductor manufacturing system is in an operating state permitting a previously installed control program to be changed, storing the transmitted control program in a memory of the controller so as to be executable by the controller, wherein a time when the semiconductor manufacturing system is performing a process event for growing a film on a substrate that is undergoing processing is not a time when the control program can be changed.

**Claim 25 (New)** The administrative server of claim 24, wherein said transmitting unit is operable to transmit the control program through the communications circuit to the controller so that the control program that is transmitted can be executed using data used to execute a previous control program.

**Claim 26 (New)** A semiconductor manufacturing system controller for controlling operation of a semiconductor manufacturing system by executing a control program, said controller comprising:

a determination unit for determining a time when a previously installed control program can be changed wherein a time when the semiconductor manufacturing system is performing a process event for growing a film on a substrate that is undergoing processing is not a time when the control program can be changed; and

a storing unit for storing a control program received through a communications circuit in a memory so as to be executable by a processor.

**Claim 27 (New)** The controller of claim 26, and further comprising:

a retaining unit for retaining existing data used to execute the previously installed control program; and

an executing unit for executing the control program received through the communications circuit using the existing data.

**Claim 28 (New)** A semiconductor manufacturing system for forming a film on a substrate that includes a controller that is operable to execute a control operation of the semiconductor manufacturing system by executing a control program, that is operable to change the control program, and that is operable to determine that a time when the semiconductor manufacturing system is performing a process event for growing a film on a substrate that is undergoing processing is not a time when the control program can be changed.

**Claim 29 (New)** The system of claim 28, wherein the controller is further operable to determine that the control program can be changed when the controller is not engaged in control processing.

**Claim 30 (New)**      The system of claim 28, wherein the controller is further operable to determine that the control program can be changed when the semiconductor manufacturing system is in a standby state immediately after being powered on.

**Claim 31 (New)**      The system of claim 28, wherein the controller is further operable to determine that the control program can be changed when a heater is standing by at a constant temperature.

**Claim 32 (New)**      The system of claim 31, wherein the controller is further operable to determine that the control program can be changed when a reaction chamber is in a standby state.

**Claim 33 (New)**      The system of claim 28, wherein the controller is further operable to determine that the control program can be changed when a robot arm or elevator is stopped.

**Claim 34 (New)**      The system of claim 28, wherein the controller is further operable to determine that the control program can be changed when a gas is not being supplied to a reaction chamber..

**Claim 35 (New)**      The system of claim 28, further comprising:  
a unit provided in the controller for receiving input of a control program change instruction from a user of the semiconductor manufacturing system; and  
a storage unit provided in the controller responsive to a control program change instruction for storing the control program in memory so as to be executable by a processor.

**Claim 36 (New)**      The system of claim 35, further comprising a retaining unit provided in said controller for retaining existing data used to execute a previously installed control program, the processor being operable to execute a replacement control program stored in memory using the existing data.